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Attorney Docket No. UMC-96-279 CON  
Client Matter No. 81848.0016.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/546,174	Confirmation No.: 4793
Application of: LIU, Chih-Chien <i>et al</i>	Customer No.: <b>25235</b>
Filed: April 11, 2000	
Art Unit: 1711	
Examiner: SERGENT, R.A.	
Attorney Docket No. UMC-96-279 CON	
For: HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	

AMENDMENT AND RESPONSE UNDER 37 C.F.R. § 1.113

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

A final Office Action was mailed in the above case June 4, 2003. Please reconsider the case in light of the following remarks.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 9 of this paper.